FIG. 1

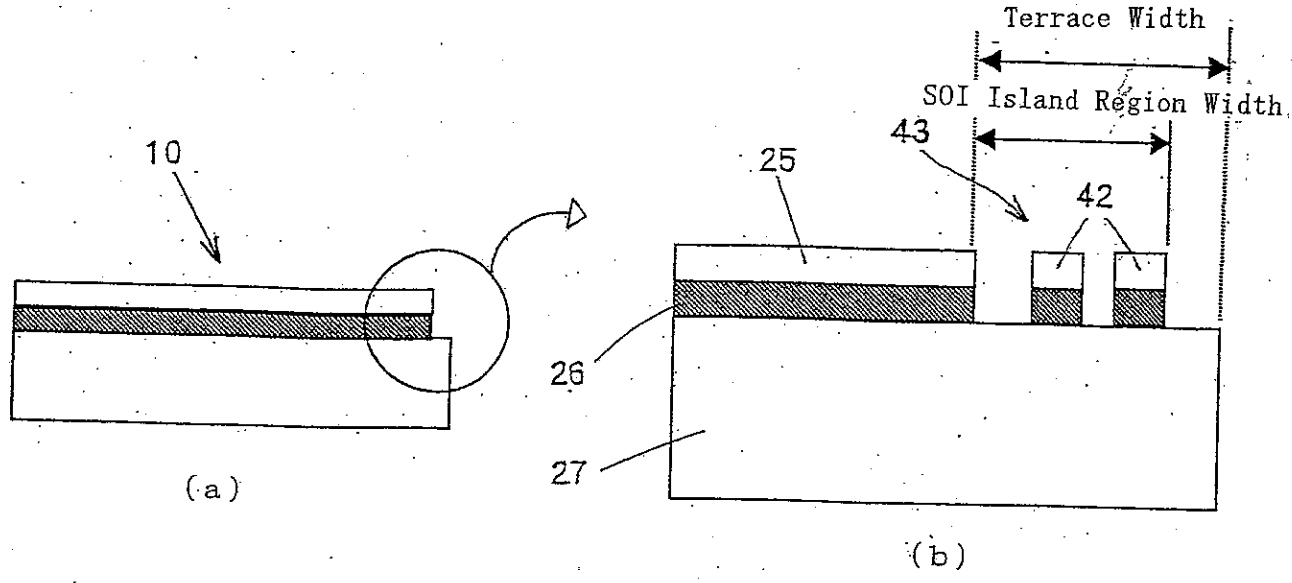
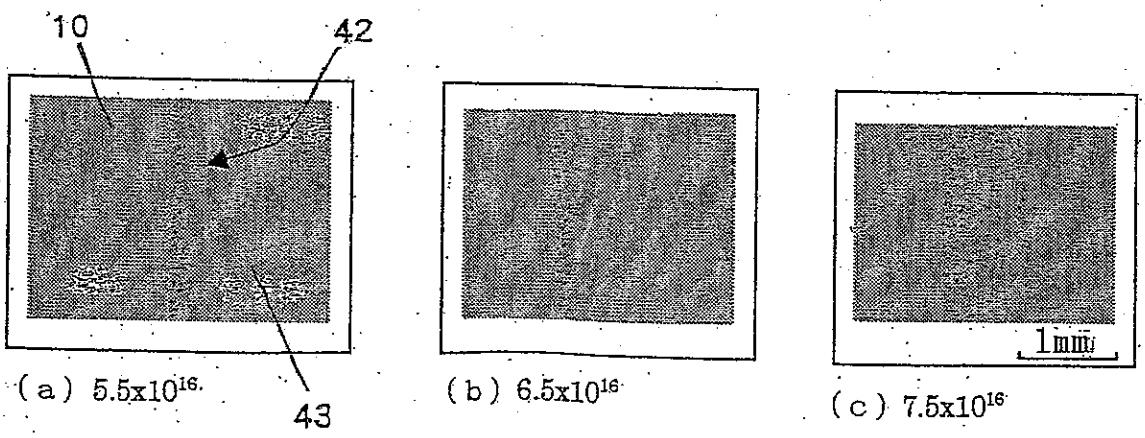


FIG. 2



Hydrogen Ion Implantation Dosage [ions/cm²]

FIG. 3

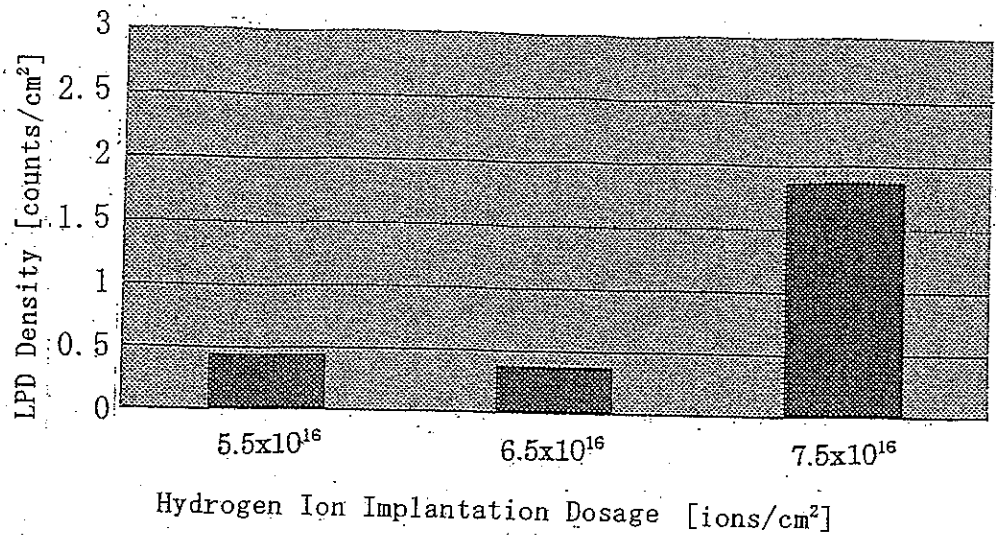
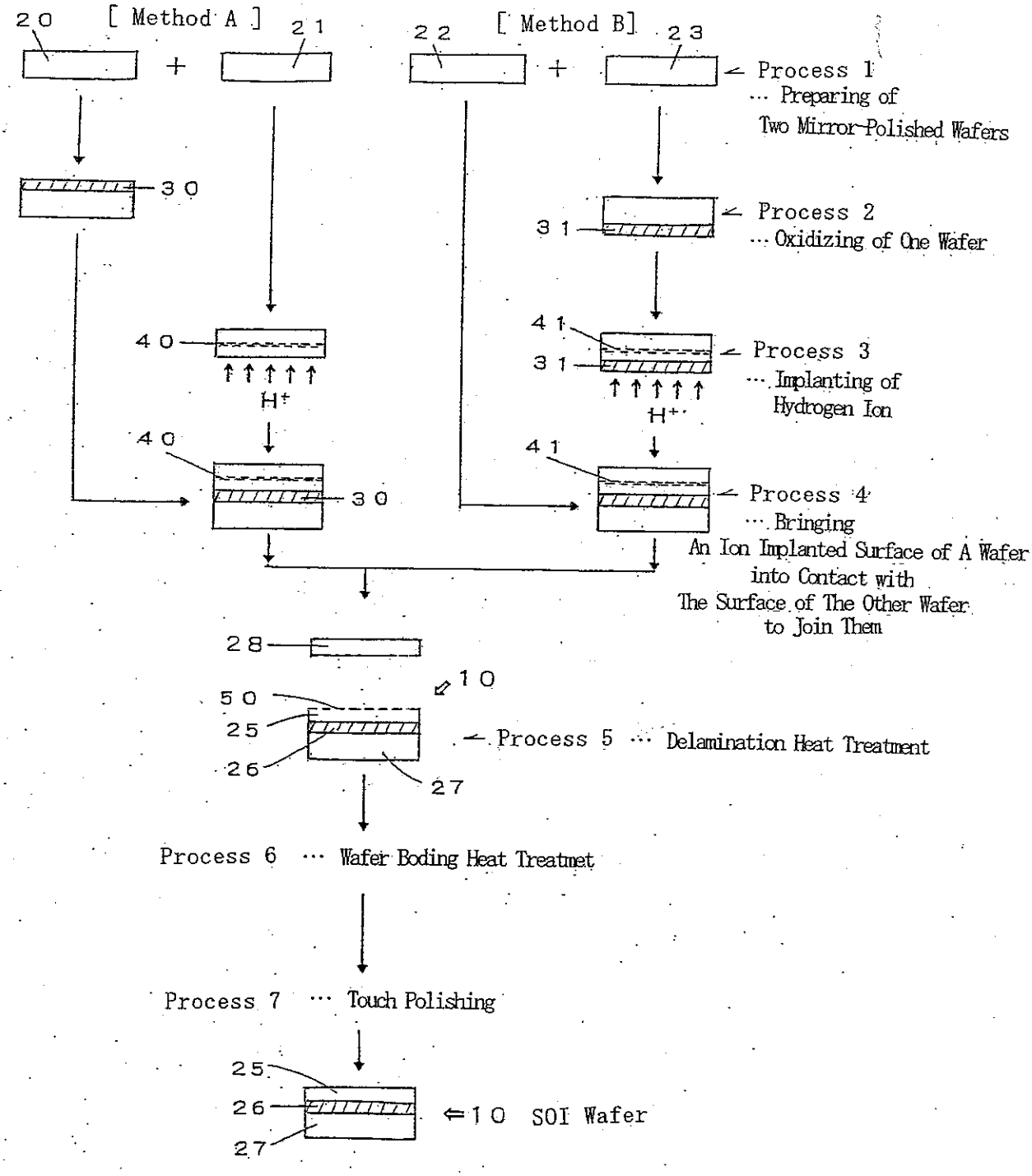

LPD Density [counts/cm²]
3
2.5
2
1.5
1
0.5
0
5.5x10¹⁶
6.5x10¹⁶
7.5x10¹⁶
Hydrogen Ion Implantation Dosage [ions/cm²]

FIG. 4


20
[Method A]
21
22
[Method B]
23
Process 1
··· Preparing of
Two Mirror-Polished Wafers
30
31
Process 2
··· Oxidizing of One Wafer
40
41
Process 3
··· Implanting of
Hydrogen Ion
H+
Process 4
··· Bringing
An Ion Implanted Surface of A Wafer
into Contact with
The Surface of The Other Wafer
to Join Them
28
10
50
25
26
27
Process 5 ··· Delamination Heat Treatment
Process 6 ··· Wafer Boding Heat Treatmet
Process 7 ··· Touch Polishing
⇐10 SOI Wafer